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PATENT

Attorney Docket No.: 019930-003710US

Client Reference No.: A1303

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Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

By: 

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Robert L. Anderson

Application No.:

Filed:

For: METHOD AND APPARATUS FOR
PROTECTING WIRING AND
INTEGRATED CIRCUIT DEVICE

Examiner:

Art Unit:

INFORMATION DISCLOSURE
STATEMENT UNDER 37 CFR §1.97 and
§1.98

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The references cited on attached form PTO/SB/08A and PTO/SB/08B are being called to the attention of the Examiner. Copies of the references are enclosed. U.S. Patent application and Office Action for related invention are listed below and copies are also included.

1. U.S. Patent Application No. 10/262,404 filed on September 30, 2002, entitled "Floating Entrance Guard for Preventing Electrical Short Circuits", inventor: David Miller.

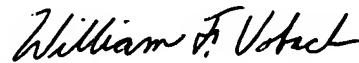
2. Office Action for Application No. 10/262,404 mailed on July 31, 2003.

It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

Applicant believes that no fee is required for submission of this statement. However, if a fee is required, the Commissioner is authorized to deduct such fee from the undersigned's Deposit Account No. 20-1430. Please deduct any additional fees from, or credit any overpayment to, the above-noted Deposit Account.

Respectfully submitted,



William F. Vobach
Reg. No. 39,411

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60196174 v1

Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>			Complete if Known		
			Application Number		
			Filing Date		
			First Named Inventor	Anderson, Robert L.	
			Art Unit		
Examiner Name					
Sheet	1	of		Attorney Docket Number	019930-003710US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code ² (if known)			
	AA	US-5,212,582	05/18/1993	Nelson	
	AB	US-5,600,383	02/04/1997	Hombeck	
	AC	US-5,960,133	09/28/1999	Tomlinson	
	AD	US-6,028,689	02/22/2000	Michalicek et al.	
	AE	US-6,040,935	03/21/2000	Michalicek	
	AF	US-6,128,122	10/03/2000	Drake et al.	
	AG	US-6,140,144	10/31/2000	Najafi et al.	
	AH	US-6,232,150 B1	05/15/2001	Lin et al.	
	AI	US-6,307,657 B1	10/23/2001	Ford	
	AJ	US-6,346,189 B1	02/12/2002	Dai et al.	
	AK	US-6,352,933 B1	03/05/2002	Forbes et al.	
	AL	US-6,437,432 B2	08-20-2002	Ikumo et al.	
	AM	US-6,469,330 B1	10/22/2002	Vigna et al.	
	AN	US-2001/0021570 A1	09/13/2001	Lin et al.	
	BO	US-2003/0174929 A1	09-18-2003	Rodgers et al.	
	BP	US-2003/0173112 A1	09-18-2003	Barnes et al.	
	BQ	US-			
	BR	US-			
	BS	US-			
	BT	US-			
	BU	US-			

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)				
	BV							<input type="checkbox"/>
	BW							<input type="checkbox"/>
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	BY							<input type="checkbox"/>
	BZ							<input type="checkbox"/>
	BAA							<input type="checkbox"/>
	CA							<input type="checkbox"/>
	CB							<input type="checkbox"/>

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

60196174 v1

Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>			Complete if Known		
			Application Number		
			Filing Date		
			First Named Inventor		
			Art Unit		
			Examiner Name		
Sheet	2	of		Attorney Docket Number	019930-003710US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	CC	AKIYAMA, TERUNOBU et al., Controlled Stepwise Motion in Polysilicon Microstructures, Journal of Microelectromechanical Systems, Vol. 2, No. 1, September 1993, pp 106-110	
	CD	ASHRUF, C.M.A. et al., Galvanic Porous Silicon Formation Without External Contracts, Elsevier Science S.A., Sensors and Actuators 74 (1999), pp. 118-122.	
	CE	BEAN, KENNETH E., Anisotropic Etching of Silicon, IEEE Transactions on Electron Devices, Vol. ED-25, No. 10, October 1978, pp 1185-1193.	
	CF	CIARLO, Dino R., A Latching Accelerometer Fabricated by the Anisotropic Etching of (110) Oriented Silicon Wafers, 0860-1317/92/010010+04104.50, March 1992 IOP Publishing Ltd.	
	CG	DEWA, Andrew S., et al., Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-6, 2000, pp. 93-96.	
	CH	FORD, JOSEPH E. et al., Wavelength Add-Drop Switching Using Tilting Micromirrors, Journal of Lightwave Technology, Vol. 17, No. 5, May 1999, pp. 904-911	
	CI	GRADE, John D., et al., A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-6, 2000, pp. 97-100	
	CJ	HOPKINS, Robert E., Some Thoughts on Lens Mounting, Optical Engineering, Vol. 15, No. 5, September-October 1976, pp. 428-430.	
	CK	KAAJAKARI, VILLE, et al., Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction, In MEMS Reliability for Critical Applications, Proceedings of SPIE Vol. 4180, 2000, pp. 60-65.	
	CL	KOCH, T.L. et al., Anisotropically Etched Deep Gratings for InP/InGaAsP Optical Devices, Journal of Applied Physics 62 (8), October 15, 1987, pp. 3461-3463.	
	CM	SCHILLING, M. et al., Deformation-Free Overgrowth of Reactive Ion Beam Etched Submicron Structures in InP by Liquid Phase Epitaxy, Applied Physics Lett. 49 (12), September 22, 1986, pp. 710-712	
	CN	TANG, WILLIAM C., et al., Electrostatically Balanced Comb Drive for Controlled Levitation, Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990, pp. 198-202	
	CO	TORCHEUX, L. et al., Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions, J. Electrochem. Soc., Vol. 142, No. 6, June 1995, pp.2037-2046	
	CP	VAN KESSEL, PETER F. et al., A MEMS-Based Projection Display, Proceedings of the IEEE, Vol. 86, No. 8, August 1998, pp. 1687-1704	
	CQ	KELLER, CHRISTOPHER, Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion, Dissertation submitted to University of California, Berkeley, Fall 1998	
	CR	MULLER, LILAC, Gimbalbed Electrostatic Microactuators with Embedded Interconnects, Dissertation submitted to University of California, Berkeley, Spring 2000	

Examiner Signature		Date Considered	
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¹ EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

² Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.